

# CERTIFICATE OF ACCREDITATION

## The ANSI National Accreditation Board

Hereby attests that

Leica Microsystems, Inc. 10 Parkway North Blvd., Suite 300 Deerfield, IL 60015

Fulfills the requirements of

ISO/IEC 17025:2017

In the field of

## **CALIBRATION**

This certificate is valid only when accompanied by a current scope of accreditation document. The current scope of accreditation can be verified at <a href="www.anab.org">www.anab.org</a>.

SDS

R. Douglas Leonard Jr., VP, PILR SBU

Expiry Date: 23 February 2024 Certificate Number: AC-1841





## SCOPE OF ACCREDITATION TO ISO/IEC 17025:2017

## Leica Microsystems, Inc.

10 Parkway North Blvd., Suite 300 Deerfield, IL 60015 Andrew Suchomski 847-821-3502

### **CALIBRATION**

Valid to: February 23,2024 Certificate Number: AC-1841

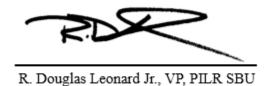
### Length - Dimensional Metrology

Parameter/Equipment	Range	Expanded Uncertainty of Measurement (+/-)	Reference Standard, Method, and/or Equipment
Widefield Microscope with Software Measurement Module	Up to 25 mm Up to 0.98 in	6 μm 240 μin	Stage Micrometer
Widefield Microscope with Caliper	Up to 2 <mark>5 mm</mark> Up to 0.98 in	13 μm 0.001 1 in	Stage Micrometer

Calibration and Measurement Capability (CMC) is expressed in terms of the measurement parameter, measurement range, expanded uncertainty of measurement and reference standard, method, and/or equipment. The expanded uncertainty of measurement is expressed as the standard uncertainty of the measurement multiplied by a coverage factor of 2 (k=2), corresponding to a confidence level of approximately 95%.

#### Notes:

- 1. On-site calibration service is available for this parameter, since on-site conditions are typically more variable than those in the laboratory, larger measurement uncertainties are expected on-site than what is reported on the accredited scope.
- 2. This scope is formatted as part of a single document including Certificate of Accreditation No. AC-1841.



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